



Optica Applicata 2007(Vol.37), No.1-2, pp. 65-72

## The method of integration of silicon - micromachined sensors and actuators to microreactor made of Foturan<sup>®</sup> glass

Paweł KNAPKIEWICZ, Rafał WALCZAK, Jan A. DZIUBAN

SEARCH

[Advanced search](#)

[About Optica Applicata](#)

[Current issue](#)

[Browse archives](#)

[Search](#)

[Editorial Board](#)

[Instructions for Authors](#)

[Ordering](#)

[Contact us](#)

### Keywords

microreaction technology, sensors integration, low temperature anodic bonding, Foturan<sup>®</sup> glass and silicon anodic bonding

### Abstract

In this article results of unique low temperature anodic bonding silicon and Foturan<sup>®</sup> glass are presented. The new method of anodic bonding can be useful in designing and fabrication of intelligent microreactors equipped with microsensors and other microdevices suitable both to control and to steer chemical process. Direct assembling onto microreactors allows to think about integrated microreactors equipped with set of sensors, *i.e.*, pressure sensors and other devices, *i.e.*, valves, flow meters, *etc.* The demand for integration microreactor with measuring /steering setup, following the technology of low temperature anodic bonding and application of this technique are described.



2.3 MB

[Back to list](#)

© Copyright 2007 T.Przerwa-Tetmajer All Rights Reserved 2007

**stat4u**

